## Amendments to the Specification:

Please replace the title as follows:

SILICON SINGLE CRYSTAL, SILICON WAFER, PRODUCTION APPARATUS

THEREFOR AND PROCESS FOR PRODUCING THE SAME

A SILICON SINGLE CRYSTAL, A SILICON WAFER, AN APPARATUS FOR PRODUCING THE SAME, AND A METHOD FOR PRODUCING THE SAME

Please replace the paragraph beginning on page 23, line 10, with the following rewritten paragraph:

Moreover, the present invention provides a method for producing a silicon single crystal by using a combined apparatus of at least two or more of the producing apparatus in which Cu concentration in a component made of quartz is determined, the producing apparatus in which Cu in devices and the like to be exposed in the furnace is determined, and the producing method apparatus in which Cu concentration of an observation window made of quartz is determined. Furthermore, the present invention provides a method for producing a silicon single crystal, wherein a silicon single crystal is grown by a combined method of the method for performing heating with a heating heater after melting of raw material and the method for cleaning HZ components in a clean environment.